

## **PATENT**

## IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re application of:	) Docket No: LAM2P257
	)
Ko et al.	) Group Art Unit: 1756
	)
Application No: 09/894,230	) Examiner: J. Ruggles
	)
Filed: June 27, 2001	) December 17, 2003
	)
For: APPARATUS AND METHOD FOR ARGON	)
PLASMA INDUCED ULTRAVIOLET LIGHT	)
CURING STEP FOR INCREASING SILICON-	)
CONTAINING PHOTORESIST SELECTIVITY	)
	CERTIFICATE OF MAILING

I hereby certify that this correspondence is being deposited with the United States Postal Service as

First Class Mail to: Commissioner for Patents P.O. Box 1450 Alexandria, VA 22313-1450 on

December 17, 2003.

Michael L. Gencarella

## <u>AMENDMENT</u>

Commissioner for Patents Washington, D.C. 20231

Dear Sir:

This Communication is in response to the Advisory Action dated November 17, 2003. A one month extension of time is hereby petitioned for, to extend the period of response to December 17, 2003. Please amend the specification and consider the following arguments:

Amendments to the Specification begin on page 2 of this paper.

A current listing of the claims are provided for the Examiner's convenience which begins on page 3 of this paper.

Remarks/Arguments begin on page 7 of this paper.